Zhe Ashley Jian

List of Publications by Year in descending order

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1478505 1474206 10 115 9 6 citations h-index g-index papers 10 10 10 165 docs citations times ranked citing authors all docs

#	Article	IF	CITATIONS
1	Temperature-dependent current-voltage characteristics of <code> <i>l^2</i> -Ga2O3</code> trench Schottky barrier diodes. Applied Physics Letters, 2020, 116, .	3.3	41
2	Chlorine-based inductive coupled plasma etching of (i) \hat{l} + (i)-Ga(sub)2(sub)O(sub)3(sub). Semiconductor Science and Technology, 2019, 34, 035006.	2.0	15
3	Deep UV-assisted capacitance–voltage characterization of post-deposition annealed Al2O3/ <i>β</i> -Ga2O3 (001) MOSCAPs. Applied Physics Letters, 2020, 116, .	3.3	14
4	Switching Performance Analysis of 3.5 kV Ga ₂ O ₃ Power FinFETs. IEEE Transactions on Electron Devices, 2021, 68, 672-678.	3.0	12
5	Characterization of MOCVD-grown AlSiO gate dielectric on \hat{l}^2 -Ga2O3 (001). Applied Physics Letters, 2021, 118, .	3.3	10
6	Investigation and optimization of HfO2 gate dielectric on N-polar GaN: Impact of surface treatments, deposition, and annealing conditions. Applied Physics Letters, 2021, 119, .	3.3	9
7	Design of ultra-scaled-channel N-polar GaN HEMTs with high charge density: A systematic study of hole traps and their impact on charge density in the channel. Journal of Applied Physics, 2020, 128, .	2.5	5
8	$\label{lem:hfosub} HfO < sub>2 < /sub> \ as\ gate\ insulator\ on\ N-polar\ GaN-AlGaN\ heterostructures.\ Semiconductor\ Science\ and\ Technology,\ 0,\ ,\ .$	2.0	4
9	Improved operational reliability of MOCVD-grown AlSiO gate dielectric on \hat{l}^2 -Ga ₂ O ₃ (001) by post-metallization annealing. Semiconductor Science and Technology, 2021, 36, 09LT03.	2.0	3
10	Demonstration of atmospheric plasma activated direct bonding of N-polar GaN and \hat{I}^2 -Ga2O3 (001) substrates. Applied Physics Letters, 2022, 120, .	3.3	2